Round Agreements Act (URAA). (See Memorandum from Joseph A. Spetrini, Richard W. Moreland, and Jeffrey P. Bialos to Robert S. LaRussa on file in the public file of the Central Records Unit, Room B–099 of the Department of Commerce).

These extensions are in accordance with section 703(c)(1)(A) of the Act (19 U.S.C. 1675(a)(3)(A)).

Dated: May 2, 1997.

### Jeffrey P. Bialos,

Principal Deputy Assistant Secretary for Import Administration.

[FR Doc. 97-12049 Filed 5-7-97; 8:45 am]

BILLING CODE 3510-DS-P

### **DEPARTMENT OF COMMERCE**

# National Institute of Standards and Technology

## Notice of a Government Owned Invention Available for Licensing

SUMMARY: The invention listed below is owned by the U.S. Government, as represented by the Department of Commerce, and is available for licensing on only a non-exclusive basis in accordance with 35 U.S.C. 207 and 37 CFR Part 404 to achieve expeditious commercialization of results of federally funded research and development.

### FOR FURTHER INFORMATION CONTACT:

Technical and licensing information on this invention may be obtained by writing to: National Institute of Standards and Technology, Industrial Partnerships Program, Building 820, Room 213, Gaithersburg, MD 20899; Fax 301–869–2751. Any request for information should include the NIST Docket No. and Title for the relevant invention as indicated below.

enter into one or more Cooperative Research and Development Agreements ("CRADA") with the licensees to perform further research on the invention for purposes of commercialization. NIST may grant licensees an option to negotiate for exclusive royalty-bearing licenses to any jointly owned inventions which arise from the CRADAs as well as an option to negotiate for exclusive royalty-bearing licenses for NIST employee inventions which arise from the CRADAs.

The invention available for licensing

NIST Docket Number: 96–009. Title: Interferometric Thickness Variation Test Method For Windows and Sili.

Abstract: This interferometric apparatus and non-contact method

measure central thickness and thickness variations of silicon wafers and other window-like optics by using a diverging wavefront and an infrared interferometer operating at a wavelength to which silicon is transparent. The speed and accuracy of the invention offer cost-effective measurements of 300 mm wafers.

Dated: May 1, 1997.

### **Elaine Bunten-Mines**,

Director, Program Office.

[FR Doc. 97-11977 Filed 5-7-97; 8:45 am]

BILLING CODE 3510-13-M

### **DEPARTMENT OF COMMERCE**

# National Institute of Standards and Technology

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this invention may be obtained by writing to: National Institute of Standards and Technology, Industrial Partnership Program, Building 820, Room 213, Gaithersburg, MD 20899; Fax 301–869–2751. Any request for information should include the NIST Docket No. and Title for the relevant invention as indicated below.

**SUPPLEMENTARY INFORMATION:** NIST may enter into a Cooperative Research and Development Agreement ("CRDA") with the licensee to perform further research on the invention for purposes of commercialization. The invention available for licensing is:

NIST Docket Number: 96–033. Title: Superconducting Transition-Edge Sensor.

Abstract: This NIST invention provides particle detection, particularly x-ray detection, using an aluminum/ normal-metal bilayer superconducting transition-edge sensor as a thermometer in a microcalorimeter. Fabrication is easier, applications are more diverse, and results are more reliable than with previous methods.

Dated: May 1, 1997.

### Elaine Bunten-Mines,

Director, Program Office.

[FR Doc. 97–11978 Filed 5–7–97; 8:45 am]

BILLING CODE 3510-13-M

### **DEPARTMENT OF COMMERCE**

# National Institute of Standards and Technology

# Visiting Committee on Advanced Technology

**AGENCY:** National Institute of Standards and Technology, Department of Commerce.

**ACTION:** Notice of partially closed meeting.

**SUMMARY:** Pursuant to the Federal Advisory Committee Act, 5 U.S.C. app. 2, notice is hereby given that the National Institute of Standards and Technology's Visiting Committee on Advanced Technology (NIST) will meet on Tuesday, June 3, 1997, from 8:30 a.m. to 5:00 p.m. The Visiting Committee on Advanced Technology is composed of 15 members appointed by the Director of the National Institute of Standards and Technology who are eminent in such fields as business, research, new product development, engineering, labor, education, management consulting, environment, and international relations. The purpose of this meeting is to review and make recommendations regarding general policy for the Institute, its organization, its budget, and its programs within the framework of applicable national policies as set forth by the President and the Congress. The agenda will include presentations on NIST programs, including an action plan to respond to the Technology Transfer Act of 1995, the status of the NIST effort to update its facilities needs assessment and the progress on developing a new master plan for the Gaithersburg and Boulder sites, NIST Budget, and a laboratory tour.

Discussions on the NIST budget, including funding levels of the Applied Technology Program (ATP), and the staffing of management positions at NIST scheduled to begin at 4:15 p.m. and to end at 5:00 p.m. on June 3, 1997, will be closed.

**DATES:** The meeting will convene June 3, 1997, at 8:30 a.m. and will adjourn at 5:00 p.m. on June 3, 1997.

ADDRESS: The meeting will be held in the Radio Building, Room 1107 (seating capacity 60, includes 35 participants), National Institute of Standards and Technology, Boulder, CO.

FOR FURTHER INFORMATION CONTACT: Chris E. Kuyatt, Executive Director, Visiting Committee on Advanced Technology, National Institute of Standards and Technology, Gaithersburg, MD 20899, telephone number (301) 975–6090.